

ICPT 2026

October 19-22, 2026

Science and Technology Convention Center,
Seoul, South Korea

October 20 (Tue.), 2026

[Oral 04] Metrology & Inspection / Equipment / Process Diagnostics

15:35-16:35

International Conference Hall (B1F)

● Session Chair: Catharina Rudolph Fraunhofer (IZM-ASSID, Germany)

15:35-15:55

[Oral 04-1]

[Robust CMP Topography Extraction via Adaptive Polynomial Selection](#)

Viorel Balan, Yorrick Exbrayat (Univ. Grenoble Alpes, France), and Sebastien Mermoz (STMicroelectronics, France)

15:55-16:15

[Oral 04-2]

[Surface-Enhanced Particle Sizing and Raman Fingerprinting for Nanoscale Abrasive and Residue Detection in Critical CMP Processes](#)

Harvey Tang and Ali Altun (UNISERS AG, Switzerland)

16:15-16:35

[Oral 04-3]

[Exploratory Data Analysis of Oscillatory Torque-Related Features in CMP Sensor Logs Associated with Slurry Formulation](#)

Kohei Noda and Hisashi Shinomura (JSR Corp., Japan)